



1763

SEC.584

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Ki-Sang KIM et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: Jeffrie Robert LUND

Filed: 26 January 1999

MULTI-CHAMBER SYSTEM
HAVING COMPACT
INSTALLATION SET-UP FOR AN
ETCHING FACILITY FOR
SEMICONDUCTOR DEVICE
MANUFACTURING

RECEIVED

JUL 18 2002

TC 1700

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RW

AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated 15 April 2002, the period for response to which is 15 July 2002, please amend the above-identified patent application as follows:

IN THE CLAIMS:

Please substitute the following claims for the pending claims with the same claim numbers.

J